



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

OKU et al

Serial No.: 09/903,764

Filed: July 13, 2001

For: FILM FORMING METHOD, SEMICONDUCTOR )  
DEVICE AND SEMICONDUCTOR DEVICE )  
MANUFACTURING METHOD )

) Examiner: Dang, T.

) Art Unit: 2823

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97(d)

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

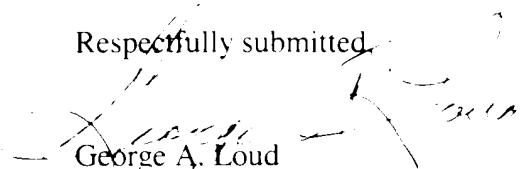
Sir:

It is respectfully requested that the examiner consider and cite of record the four (4) references listed on the attached, copies of which are submitted herewith. Also submitted herewith is a copy of a European Search Report issued July 23, 2003 in connection with EP Application No. 01 11 66 94, believed to correspond to the captioned application. The examiner will note that in addition to the four references submitted here, the European Search Report cites a fifth reference, i.e., the English language abstract of Japanese Publication 10-125669 which has already been made of record by the office action of October 24, 2002.

The undersigned hereby certifies that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three (3) months prior to today's date.

Our credit card payment form in the amount of \$180.00 is also submitted herewith to cover the fee required by 37 CFR 1.17(p).

Respectfully submitted,

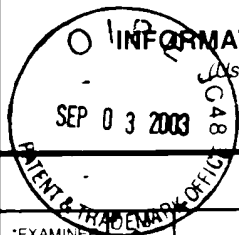
  
George A. Loud

Reg. No. 25,814

Dated: September 3, 2003

LORUSSO, LOUD & KELLY  
3137 Mount Vernon Avenue  
Alexandria, VA 22305

(703) 739-9393

**INFORMATION DISCLOSURE CITATION**

(Use several sheets if necessary)

ATTY DOCKET NO.

OKA-C104

SERIAL NO.

09/903,764

OKU et al

FILING

07/13/2001

GROUP

2823

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	4,282,268	8/4/81	PRIESTLEY et al	427	39	

**FOREIGN PATENT DOCUMENTS**

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	0 664 560 A2	18/01/95	EP				

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

		Vestiel et al, "A Low Dielectric Film Obtained by Polymerization of..."; 30th European Microwave Conf. Proceed., Paris, Oct. 3-5, 2000, Vol., 3 of 3, Conf. 30, 5 Oct 2000 pgs 233-236
		Bogart et al, "Deposition of SiO <sub>2</sub> Films from Novel Alkoxysilane/O <sub>2</sub> Plasmas", Jorنال of Vacuum Science and Technology, Part A, American Institute of Physics, Vol. 16, No. 6, November 1998 (1998-11), Pages 3175-3184

EXAMINER

DATE CONSIDERED

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.